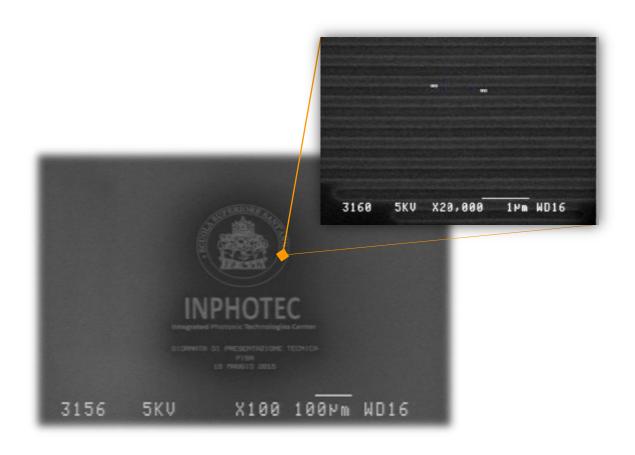




INPHOTEC

INTEGRATED PHOTONIC TECHNOLOGY CENTER





Vision/Mission/Goal





Mission:

- ■To provide center of competence
- Fabrication facilities and technologies platforms for research
- ■Prototyping and production of high added value components and circuits to academic and industrial SME

Goal:

The major areas where INPHOTEC can provide innovative front end and back end processes and technologies are:

- Photonic integrated circuits and optoelectronics
- ■Bio photonics and medical
- Sensors and MEMS, MOEMS

Goal Vision

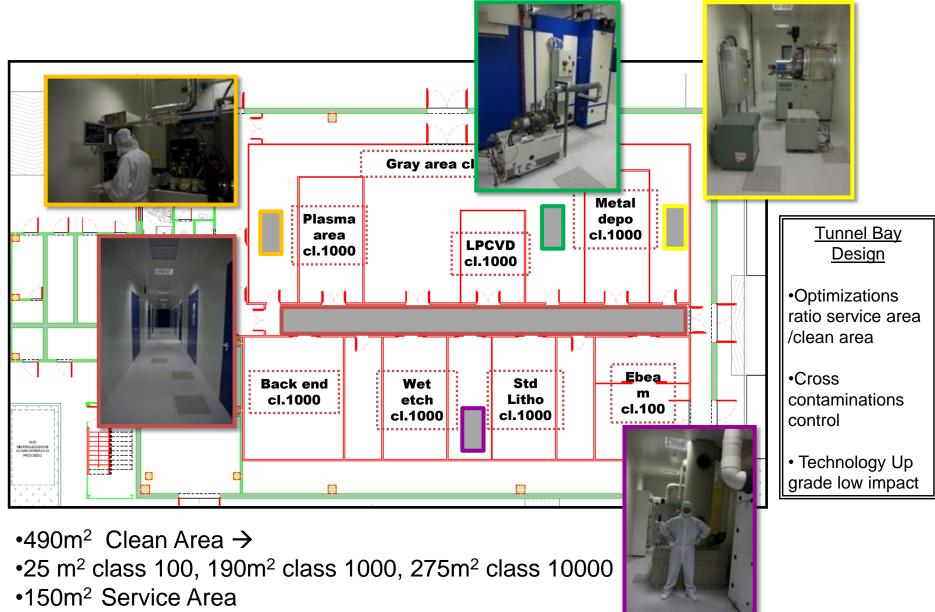
Vision:

- ■To create value through innovation developing proprietary solutions
- ■To have high flexibility and reduced tooling and set-up costs
- ■To focus on small and medium production level to support industries



Infrastructure: Clean room







Infrastructure: Advanced Packaging Lab

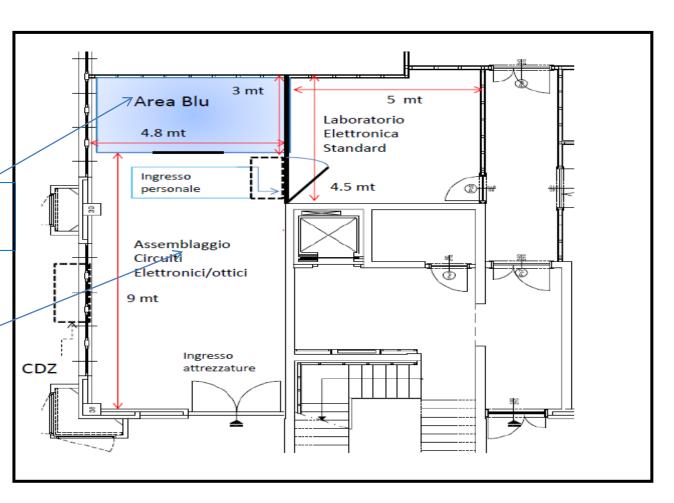




CR: Class 100 T°C 21± 1°C

> CR: Class 10000 T°C 21± 2°C







Technology Platforms



- Silicon photonics
- OHybrid Integration
- oGlass on silicon
- Advanced packaging





DEVELOPMENT OF PROPRIETARY SOLUTIONS

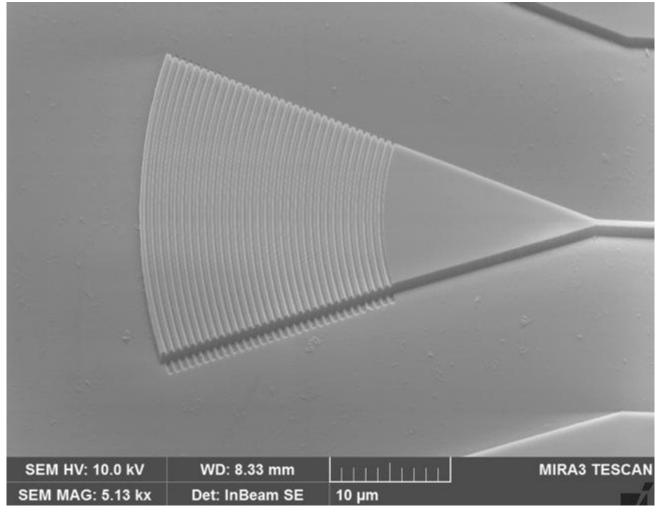
PROTOTIPATIONS UP TO THOUSANDS PIECES/YEAR







Technology Platform Silicon Photonics

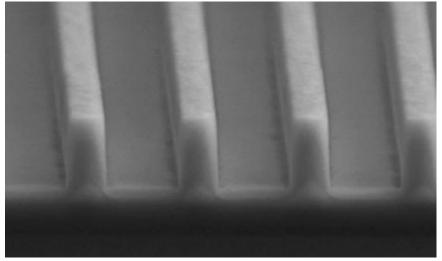


Waveguide Grating coupling Structure for silicon photonics



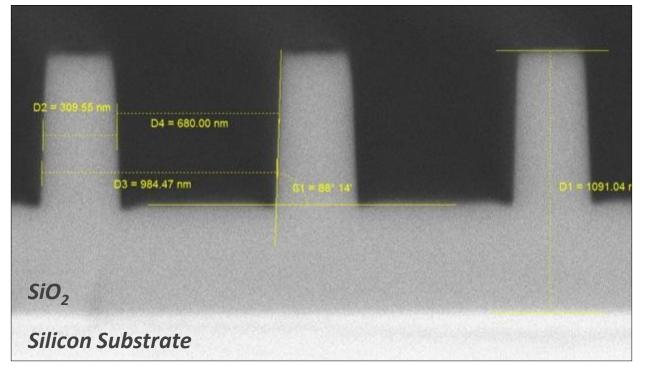
SUB-MICRON ETCHING OF DIELECTRICS





DEEP ETCHING of PECVD - SiO₂ with Soft Mask (e-Beam)

Etch Depth = 650 nm



Grating Size: 310/680 nm

88° Sidewalls

Development in Progress



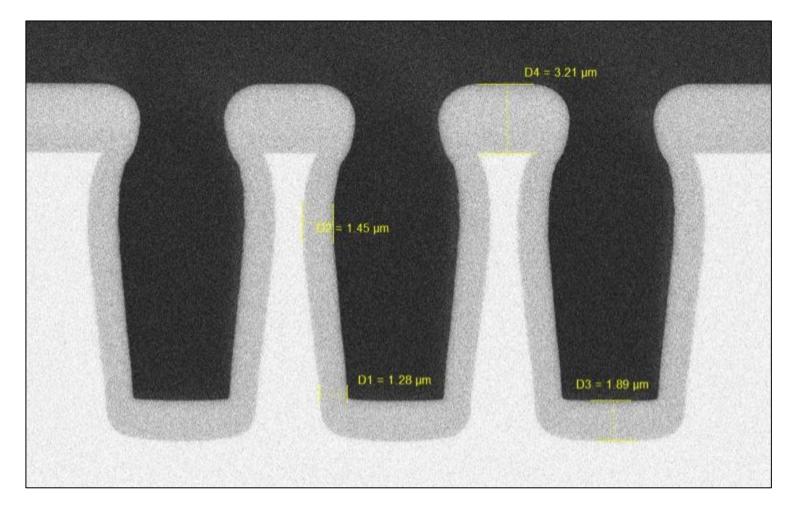
DEPOSITION OF THICK TEOS BY PECVD



Conformal deposition

PECVD deposition from liquid precursors.

Thick depositions are possible (several microns)





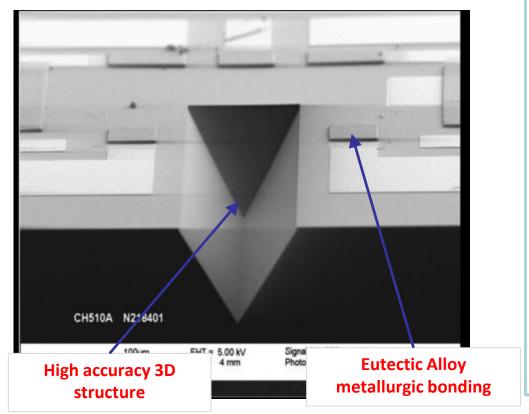
Technology Platform: Hybrid Integration



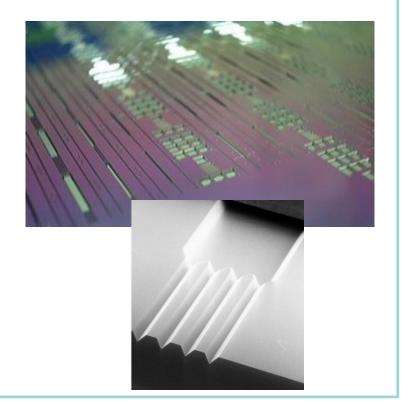
The "Hybrid Integration" Platform aims to develop technologies that can suit the necessity to integrate different devices and parts together, enabling compactness and interoperability.

In particular the Platform will develop the use of micro structured silicon as the SiOB Silicon Optical Bench.

Optical submount



Fiber block





Technology Platform: Advanced packaging



Design, development, prototipation, small production packaging line on:

- silicon photonics and optoelectronics components,
- sensors,
- MEMS, MOEMS.



- Datacom,
- Internet of Things and 5G
- Medical
- Biotechnology





MAIN EQUIPMENT

MAIN PROCESSES

- 1 automatic die-attach FINETECH PICO
- 1 manual Wire Bonder TPT model HB16
- 1 Automatic ball wire bonder K&S
- 1 Automatic Alignment and Pigtailing Bench
- 1 Splicer FUJIKURA (PM fibers)
- 1 Stereo microscope,
- 1 Chemical Hood, cleaning
- 1 Pull-shear tests XYZTEC model Condor EZ

- Vertical and horizontal alignment and pigtailing
- Lenses and Fiber Ribbon Alignment and Pigtail
- Die Bonding, Flip-Chip Bonding,
- Tacking, In situ reflow, Eutetic bonding
- Thermocompression
- Single-Step solder ball placement
- Flux less / solder paste / void free soldering
- Wafer bump reflow
- Wire and ribbon bonding

MAIN EQUIPMENT from january 2016

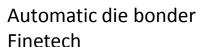
- 1 automatic flip chip machine submicron accuracy
- 1 solder reflow oven with vacuum and reduced atmosphere
- 1 thermal cycling equipment





Technology Platform: Advanced Packaging







Automatic ball bonder K&S



Automatic pigtailing/flip chip bench PI-miCos

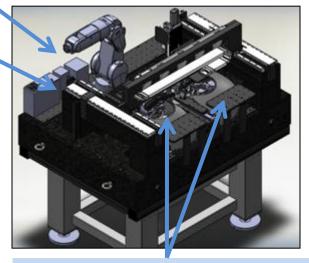


Automatic alignment bench for Si photonic chips pigtailing



Robot

Pick-up station



Submicron precision positioners = SpaceFABs – 6 axis each



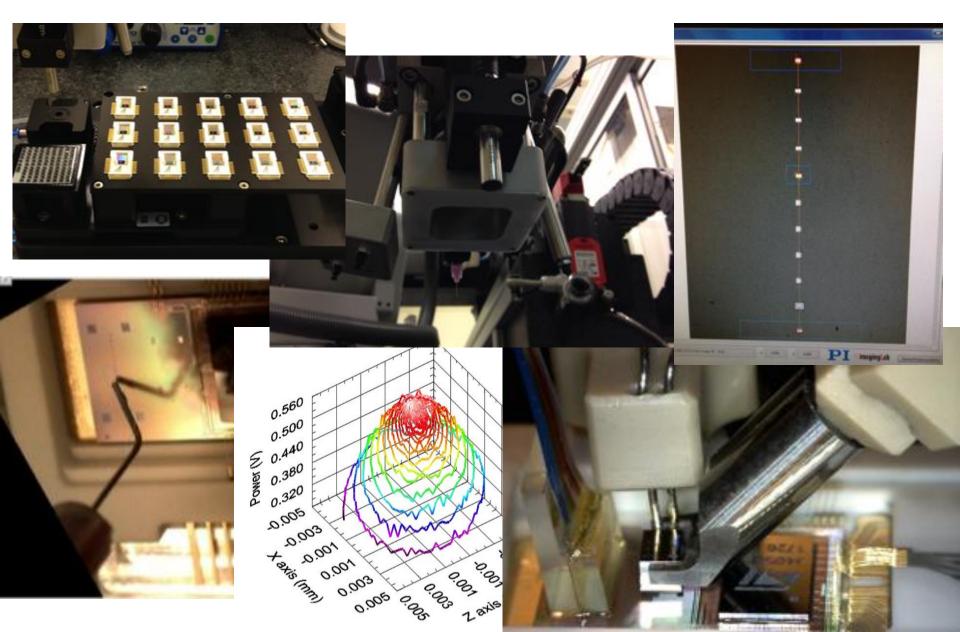
Automatic pigtailing/flip chip bench PI-miCos – Photo in our lab

- Bench designed for fibers and lenses pigtailing
- Robot used for component pick-up, vision, glue dispensing and UV curing
- Two submicron precision SpaceFAB positioners are used
- Vision assisted passive pre-alignment
- Active alignment performed using power monitoring
- Bench is designed to be flexible → allows different kind of chips/packages/fibers to be used



Inphotec Advanced Packaging Examples

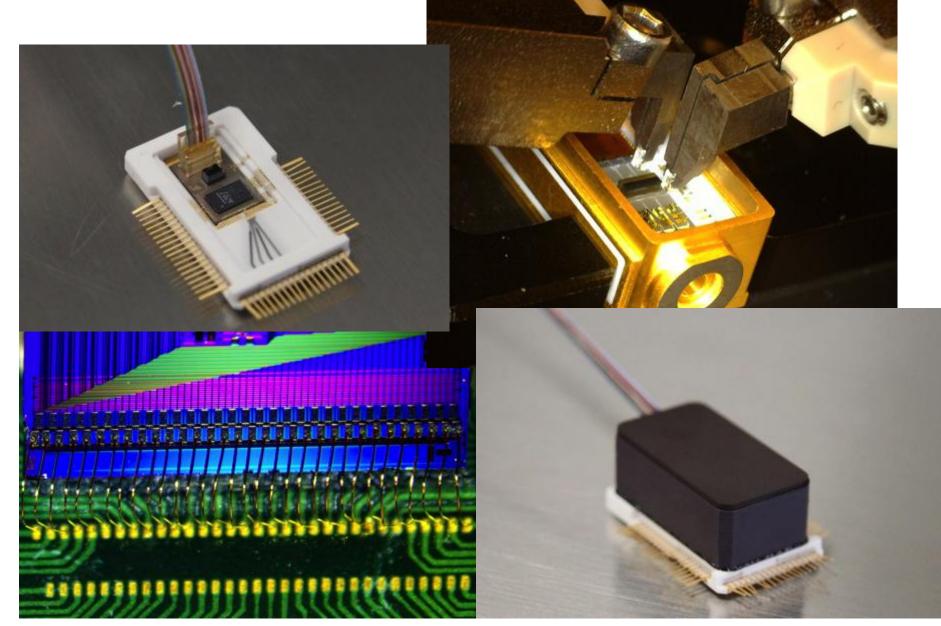






Inphotec Advanced Packaging Examples









ACTIVE PROJECTS AND CONTRACTS

Short History:

- > Packaging Platform started activity January 2014
- ➤ Inphotec Facilities completed December 2014
- ➤ Inphotec Center Full Activities Started January 2015

European Projects	
Customers	

Cooperations

IRIS (2014-2016)

TUB BERLIN

ERICSSON

ROAM (2014-2016)

IZM FRAUNHOFER

MICROELECTRONICS

TERABOARD (2016-2018)

IHP MICROELECTRONICS

HUAWEI (CHINA)

MULTIPHOTON

(GERMANY)

IHP

ST

MICROELECTRONICS

MC GILL UNIVERSITY (CANADA)

CPqD (BRASIL)

CMC (CANADA)

GRAPHENE FLAGSHIP



Conclusion





Infrastructure

Team













thank you!

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